



Sheet 1 of 1

Form 1449*	Atty. Docket No.: 303.610US1	Serial No. 09/382,524
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Paul A. Farrar	
	Filing Date: August 25, 1999	Group: Unknown

## U.S. PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
PS	5,470,802	11/28/1995	Gnade, B.E., et al.	437	238	05/20/94
	5,473,814	12/12/1995	White, L.H.	29	840	01/07/94
	5,747,880	05/05/1998	Havemann, R.H., et al.	257	759	11/18/96
	5,786,630	07/28/1998	Bhansali, A., et al.	257	697	08/07/96
	5,844,317	12/01/1998	Bertolet, A., et al.	257	773	07/26/96

## FOREIGN PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes   No
-----------------------	-----------------	------	---------	-------	----------	-------------------------

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

PS	Chiniwalla, N., et al., "Structure-Property Relations for Polynorbornenes", <u>Proceedings from the Eighth Meeting of the Dupont Symposium on Polymides In Microelectronics</u> , pp. 615-642, (1998)	✓
	Jayaraj, K., et al., "Low Dielectric Constant Microcellular Foams", <u>Proceedings from the Seventh Meeting of the DuPont Symposium on Polymides in Microelectronics</u> , pp. 474-501, (September 1996)	✓
	Miller, R.D., et al., "Low Dielectric Constant Polyimides and Polyimide Nanofoams", <u>Seventh Meeting of the DuPont Symposium on Polymides in Microelectronics</u> , pp. 443-473, (September 1996)	✓
	Shibasaki, T., et al., "Process and Application of Fumed Silica AEROSIL", <u>3rd Annual Workshop on Mechanical Polishing</u> , Lake Placid, New York, pp. 1-27, (1998)	✓
	Ting, C.H., "Low K Material/Process Development", <u>1996 VLSI Multilevel Interconnection State-of-the-Art Seminar</u> , pp. 171-212, (June 1996)	✓
	Van Vlack, L.H., <u>Elements of Materials Science</u> , Addison-Wesley Publishing Co., Inc. Reading, MA, pg. 468, (1959)	✓
	Vardaman, E.J., "Future Packaging Trends: CSP vs. Flip Chip", <u>11th European Microelectronics Conference</u> , pp. 295-299, (1997)	✓

Examiner: ESUA Asrahan Date Considered: 7/10/01

\*Substitute Disclosure Statement Form (PTO-1449)

\*\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

RECEIVED  
MAY 30 2001  
TC 2800 MAIL ROOM



Sheet 1 of 1

Form 1449\*

Atty. Docket No.: 303.610US1

Serial No. 09/382,524

INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(Use several sheets if necessary)

Applicant: Paul A. Farrar

Filing Date: August 25, 1999

Group: 2813

## U. S. PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
PN	5,227,103	07/13/1993	Muschiatti, L.C.	264	45.9	02/27/92
	5,591,676	01/07/1997	Hughes, et al.	437	195	03/16/95
	5,780,121	07/14/1998	Endo, K.	427	569	06/12/97
	5,821,621	10/13/1998	Jeng, S.	257	759	10/10/96
	5,830,923	11/03/1998	Venkataramm, S.K.	521	64	04/17/97
	6,077,792	06/20/2000	Farrar, P.A.	438	780	07/14/97

## FOREIGN PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes   No
	2158995A	11/20/1985	Great Britain	H01Q	17/00	

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

PN	1	In: Metals Handbook Ninth Edition, Volume 2 Properties and Selection: Nonferrous Alloys and Pure Metals, ASM International, pp. 796-797, (1979)
	1	"ACCUSPIN T-18 Flowable Spin-On Polymer (SOP)", AlliedSignal - Advanced Microelectronic Materials, Sunnyvale, CA, pp. 1-2, (7/98)
	1	Conti, R., et al., "Processing Methods to Fill High Aspect Ratio Gaps Without Premature Constriction", 1999 Proceedings of Dielectrics for Multilevel Interconnection Conference, pp. 201-209, (1999) ✓
	1	Craig, J.D., "Polyimide Coatings", In: Packaging, Electronic Materials Handbook, Vol. 1, ASM International Handbook Committee (eds.), ASM International, Materials Park, OH, 767-772, (1989) ✓
	1	Remenar, J., et al., "Templating Nanopores into Poly (Methylsilsesquioxane): New-Low Dielectric Coatings Suitable for Microelectronic Applications", Materials Research Society Symposium Proceedings, 511, pp. 69-74, (1998) ✓
	1	Volksen, W., et al., "Characterization and Processing Considerations for Methylsilsesquioxane Based Dielectrics", Proceedings of the Fifth Dielectric for ULSI Multilevel Interconnections, Santa Clara, CA, pp. 83-90, (1999) ✓

RECEIVED  
NOV 20 2000  
TECHNOLOGY CENTER 2800

Examiner

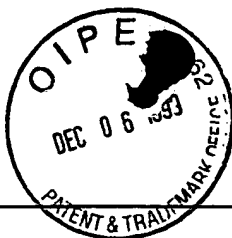
Fehar Abraham

Date Considered

7/10/01

\*Substitute Disclosure Statement Form (PTO-1449)

\*\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Sheet 1 of 2

Form 1449*	Atty. Docket No.: 303.610US1	Serial No. 09/382,524
INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use several sheets if necessary)	Applicant: Paul A. Farrar	
	Filing Date: August 25, 1999	Group: 2812

## U.S. PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
Pd	3,953,566	04/27/1976	Gore, R.W.	264	288	07/03/73
	3,962,153	06/08/1976	Gore, R.W.	260	2.5R	06/14/73
	4,096,227	06/20/1978	Gore, R.W.	264	210R	12/03/75
	4,482,516	11/13/1984	Bowman, J.B., et al.	264	127	09/10/12
	4,962,058	10/09/1990	Cronin, J.E., et al.	437	187	04/14/89
	5,158,986	10/27/1992	Cha, S.W., et al.	521	82	04/05/91
	5,158,989	10/27/1992	Ogitani, O., et al.	522	77	10/09/90
	5,173,442	12/22/1992	Carey, D.H.	437	173	03/24/92
	5,334,356	08/02/1994	Baldwin, D.F., et al.	422	133	08/24/92
	5,340,843	08/23/1994	Tsuruta, M., et al.	521	79	02/22/93
	5,449,427	09/12/1995	Wojnarowski, R.J., et al.	156	155	05/23/94
	5,486,493	01/23/1996	Jeng, S.	437	195	04/26/95
	5,554,305	09/10/1996	Wojnarowski, R.J., et al.	216	62	03/27/95
	5,593,926	01/14/1997	Fujihira, M.	437	209	10/07/94
	5,785,787	07/28/1998	Wojnarowski, R.J., et al.	156	155	11/22/95
	5,864,923	02/02/1999	Rouanet, S.F., et al.	23	295R	08/26/97
	5,879,794	03/09/1999	Korleski, J.E.	428	317.1	11/08/96
	5,891,797	04/06/1999	Farrar, P.A.	438	619	10/20/97

## FOREIGN PATENT DOCUMENTS

**Examiner Initial	Document Number	Date	Country	Class	Subclass	Translation Yes   No
-----------------------	-----------------	------	---------	-------	----------	-------------------------

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

Pd	1	"Packaging", In Electronic Materials Handbook, Vol 1, ASM International, 105, 768-769, (1989)
		"Properties and Selection: Nonferrous Alloys and Pure Metals", Metals Handbook Ninth Edition, Vol. 2, ASM International, 157, 395, (1979)
		Jin, C., et al., "Porous Xerogel Films as Ultra-low Permittivity Dielectrics for ULSI Interconnect Applications", Advanced Metallization and Interconnect Systems for ULSI Applications, Boston, MA, 463-469, (October 1996)
		Ramos, T., et al., "Nanoporous Silica for Dielectric Constant Less Than 2", Advanced Metalization and Interconnect Systems for ULSI Applications, Boston, MA, 455-461, (October 1996)

Examiner <u>Fetsum Assef</u>	Date Considered <u>7/10/01</u>
------------------------------	--------------------------------

\*Substitute Disclosure Statement Form (PTO-1449)

\*\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Sheet 2 of 2

Form 1449\*

Atty. Docket No.: 303.610US1

Serial No. 09/382,524

INFORMATION DISCLOSURE STATEMENT  
BY APPLICANT

(Use several sheets if necessary)

Applicant: Paul A. Farrar

Filing Date: August 25, 1999

Group: 2812

## OTHER DOCUMENTS

(Including Author, Title, Date, Pertinent Pages, Etc.)

\*\*Examiner  
Initial

Rr

Singer, P., "The new low-k candidate: It's a gas", Semiconductor International, 22(3), 38, (Mar 1999)

RECEIVED

DEC 07 1999

TECHNOLOGY CENTER 2800

Examiner

F. H. Horch

Date Considered

7/10/01

\*Substitute Disclosure Statement Form (PTO-1449)

\*\*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.